SEMICONDUCTOR DEVICE AND PRODUCTION METHOD

CROSS-REFERENCE TO RELATED APPLICATION

[0001] This application claims the benefit of Japanese Patent Application No. 2010-136470 filed June 15, 2010, the entire disclosure of which is incorporated by reference herein.

FIELD

[0002] This application relates generally to a semiconductor device and a method of producing such.

BACKGROUND

[0003] Semiconductor devices, particularly integrated circuits using MOS transistors, are increasingly being highly integrated. MOS transistors in integrated circuits have been downsized to nano sizes as the integration level is increased. As MOS transistors are downsized, problems arise such as difficulty in leaking current control. For that reason, further downsizing is difficult. In order to resolve these problems, a surrounding gate transistor (SGT) structure has been proposed in which the source, gate and drain are provided on a substrate in the vertical direction and the gate surrounds an island-shaped semiconductor layer.

[0004] In order to reduce power consumption in SGTs, it is preferable for resistance to be reduced in the source, gate and drain. In particular, in reducing the resistance of the gate electrode, it is desirable to use metal in the gate electrode. However, contamination of manufacturing equipment by metal and contamination of semiconductor devices produced by that manufacturing equipment is not desirable. Accordingly, processes subsequent to the forming of the metal gate electrode need to be special processes such as those that constantly control such metal contamination.

[0005] Patent Literature 1 discloses a method for producing an SGT satisfying to a certain extent the various conditions stated above.

[Background Art]

[Patent Literature]

[0006] [Patent Literature 1] International Laid-Open Patent Publication 2009/110049

[Summary of the Invention]

[0007] However, in Patent Literature 1 the protection of semiconductor manufacturing equipment and semiconductor devices from metal contamination is imperfect. For example, in Patent Literature 1 the gate electrode is formed by planarizing the gate metal using CMP (Chemical Mechanical Polishing) and then etching this material. At this time, the gate metal is not covered by other materials and is exposed. In addition, the gate metal is similarly exposed during the process of wet etching the nitride film hard mask and nitride film sidewall. Consequently, there is a concern that the CMP device, the gate etching device and the nitride film wet etching device could be contaminated by metal in the course of producing the SGT. Hence, there is a possibility that a semiconductor device produced through such a metal device could be contaminated by metal.

[0008] In addition, when forming a metal-semiconductor compound through etching in Patent Literature 1, the gate metal is exposed. Consequently, per Patent Literature 1, the gate metal needs to be tantalum or some other material that is not etched by the chemicals used when forming the metal-semiconductor compound.

[0009] In addition, another problem is that similar to MOS transistors, as SGTs are downsized parasitic capacitance occurs in the multi-layered wiring and through this the operating speed of the SGT declines.

[0010] In consideration of the foregoing, it is an objective of the present invention to provide a semiconductor device having a structure that controls metal contamination of semiconductor manufacturing equipment and semiconductor devices in semiconductor manufacturing processes while having good characteristics, and a method of producing such a device.

SUMMARY

[0011] The semiconductor device according to a first aspect of the present invention is a semiconductor device provided with:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the first planar semiconductor layer and the lower region of the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround the upper region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film;

a first contact formed above the first columnar semiconductor layer;

a second contact formed above the first planar semiconductor layer; and

a third contact formed above the first gate electrode;

wherein the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film.

[0012] It is preferable for the thickness of the second insulating film to be thicker than the sum of the thickness of the first gate insulating film and the thickness of the first metal film.

[0013] It is preferable for the semiconductor device to further have a first metal-semiconductor compound formed on the upper surface of the first high concentration semiconductor layer.

[0014] It is preferable for the length from the center of the first columnar semiconductor layer to the edge of the first planar semiconductor layer to be larger than the sum of the length from the center to the sidewall of the first columnar semiconductor layer, the thickness of the first gate insulating film, the thickness of the first gate electrode and the thickness of the third insulating film.

[0015] It is also possible for the semiconductor device to further have a third metal-semiconductor compound formed on the top surface of the first gate electrode.

[0016] It is also possible for the semiconductor device to further have a second metal-semiconductor compound formed on the top surface of the second high concentration semiconductor layer.

[0017] The semiconductor device according to a second aspect of the present invention is provided with a first transistor and a second transistor, wherein:

the first transistor has:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer of second conductive type formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of second conductive type formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration

semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround upper region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film;

a first metal-semiconductor compound formed on the top surface of the portion of the first high concentration semiconductor layer formed in the region below the first columnar semiconductor layer;

a third metal-semiconductor compound formed on the top surface of the first gate electrode; and,

a second metal-semiconductor compound formed on the top surface of the second high concentration semiconductor layer;

and the second transistor has:

a second planar semiconductor layer;

a second columnar semiconductor layer formed on the second planar semiconductor layer;

a third high concentration semiconductor layer of first conductive type formed on the lower region of the second columnar semiconductor layer and on the region of the second planar semiconductor layer below the second columnar semiconductor layer;

a fourth high concentration semiconductor layer of first conductive type formed on the upper region of the second columnar semiconductor layer;

a second gate insulating film formed on the sidewall of the second columnar semiconductor layer between the third high concentration semiconductor layer and the fourth high concentration semiconductor layer, so as to surround the second columnar semiconductor layer;

a second metal film formed on the second gate insulating film so as to surround the second gate insulating film;

a second semiconductor film formed on the second metal film so as to surround the second metal film;

a second gate electrode composed of the second metal film and the second semiconductor film;

a fourth insulating film formed between the second gate electrode and the second planar semiconductor layer;

a fifth insulating film formed in sidewall shape contacting the upper sidewall of the second columnar semiconductor layer and the top surface of the second gate electrode so as to surround the top region of the second columnar semiconductor layer;

a sixth insulating film formed in a sidewall shape contacting the sidewall of the fourth insulating film and the second gate electrode so as to surround the second gate electrode and the fourth insulating film;

a fourth metal-semiconductor compound formed on the top surface of the portion of the third high concentration semiconductor layer formed in the region below the second columnar semiconductor layer;

a fifth metal-semiconductor compound formed on the top surface of the second gate electrode; and,

a sixth metal-semiconductor compound formed on the top surface of the fourth high concentration semiconductor layer;

wherein the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film, and

the second gate insulating film and the second metal film are covered by the second columnar semiconductor layer, the second semiconductor film, the fourth insulating film and the fifth insulating film.

[0018] It is preferable for the first gate insulating film and the first metal film to be formed from materials that make the first transistor enhancement-type, and

the second gate insulating film and the second metal film to be formed from materials that make the second transistor enhancement-type.

[0019] It is preferable for the thickness of the second insulating film to be thicker than the sum of the thickness of the first gate insulating film and the thickness of the first metal film.

[0020] It is also possible for the semiconductor device to be such that the length from the center of the first columnar semiconductor layer to the edge of the first planar semiconductor layer is larger than the sum of the length from the center to the sidewall of the first columnar semiconductor layer, the thickness of the first gate insulating film, the thickness of the first gate electrode and the thickness of the third insulating film.

[0021] It is also possible for the semiconductor device to be such that:

the first conductive type is n+ type,

the second conductive type is p+ type, and

the first and second columnar semiconductor layers and the first and second planar semiconductor layers are made of silicon

[0022] The method of producing a semiconductor device according to a third aspect of the present invention is a method of producing the semiconductor device according to the present invention and includes:

a process for preparing a first structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer and a hard mask formed on the top surface of the first columnar semiconductor;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer; and

a first insulating film formed on the first planar semiconductor layer;

a process for forming a seventh insulating film, a third metal film and a third semiconductor film, in that order, on the first structure;

a process for etching the third semiconductor film and leaving a sidewall shape on the sidewall on the first columnar semiconductor layer;

a process for etching the third metal film and leaving a sidewall shape on the sidewall of the first columnar semiconductor layer;

a seventh insulating film etching process for etching the seventh insulating film and leaving a sidewall shape on the sidewall of the first columnar semiconductor layer; and

a fourth semiconductor film formation process for forming a fourth semiconductor film on the result of the seventh insulating film etching process.

[0023] It is also possible for the semiconductor device production method according to the present invention to include:

a process for planarizing the fourth semiconductor film and the third semiconductor film in the result of the fourth semiconductor film formation process and exposing the upper region of the first metal film;

a first metal film and first gate insulating film formation process for etching the third metal film and the seventh insulating film so that the upper sidewall of the first columnar semiconductor layer is exposed to form the first metal film and the first gate insulating film; and,

a process for forming a first oxide film on the result of the first metal film and first gate insulating film formation process.

[0024] The method of producing a semiconductor device according to a fourth aspect of the

present invention is a method of producing the semiconductor device according to the present invention and includes:

a process for preparing a second structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall in the middle region of the first columnar semiconductor layer so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film; and

a first insulating film formed between the first gate electrode and the first planar semiconductor layer; and

a process for forming a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer on the upper region of the first columnar semiconductor layer on the second structure by injecting a dopant at an angle of 10 degrees to 60 degrees, with a line orthogonal to the substrate being 0 degrees.

[0025] The method of producing a semiconductor device according to a fifth aspect of the present invention is a method of producing the semiconductor device according to the present invention and includes:

a process for preparing a third structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film; and

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a process for forming an eighth insulating film on the third structure; and

a process for forming a second insulating film by etching the eighth insulating film in a sidewall shape so the eighth insulating film remains on the top surface of the first gate electrode and the upper sidewall of the first columnar semiconductor layer.

[0026] The method of producing a semiconductor device according to a fifth aspect of the present invention is a method of producing the semiconductor device according to the present invention and includes:

a process for preparing a fourth structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below

the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround the top region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film; and

a first gate wire connected to the first gate electrode;

a contact stopper formation process for forming a contact stopper on the fourth structure;

a process for forming an interlayer insulating film so as to bury the result of the contact stopper formation process;

a process for forming a first resist on the interlayer insulating film, excluding on top of the first columnar semiconductor layer;

a process for etching the interlayer insulating film and forming a first contact hole on the interlayer insulating film;

a first resist removal process for removing the first resist;

a process for forming a second resist on the result of the first resist removal process, excluding on the first planar semiconductor layer and on the first gate wire;

a process for etching the interlayer insulating film and forming a second contact hole on top of the first planar semiconductor layer and forming a third contact hole on top of the first gate wire, on the interlayer insulating film;

a process for removing the second resist; and

a process for forming a first contact positioned above the first columnar semiconductor layer, a second contact positioned above the first planar semiconductor layer and a third contact positioned above the first gate wire on the first contact hole, the second contact hole and the third contact hole, respectively.

[Efficacy of the Invention]

[0027] In the present invention, the semiconductor device is provided with:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the first planar semiconductor layer and the lower region of the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround the upper region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film;

a first contact formed above the first columnar semiconductor layer;

a second contact formed above the first planar semiconductor layer; and

a third contact formed above the first gate electrode;

and the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film.

Through this, an SGT structure is provided that uses metal in the gate electrode while controlling metal contamination, lowers the resistance of the gate, source and drain, and reduces parasitic capacitance.

The first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film.

If the metal film is exposed when the metal-semiconductor compound is formed, the metal film is etched by a mixture, such as, a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture when the metal-semiconductor compound is formed. However, in the structure of the present invention, the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film, so the first metal film is not etched by the sulfuric

acid hydrogen peroxide mixture or the ammonia hydrogen peroxide mixture when the compound of metal and semiconductor is formed. Through this, it is possible to form a metal-semiconductor compound on the first high concentration semiconductor layer, the first gate electrode and the second high concentration semiconductor layer, it is possible to control depletion of the channel region by using metal in the gate electrode, to reduce gate electrode resistance and to reduce the resistance of the gate, source and drain through a compound of metal and silicon. In addition, it is possible to reduce parasitic capacitance between the gate electrode and the planar semiconductor layer by means of the first insulating film.

In addition, the first gate insulating film and the first metal film are formed only surrounding the first columnar semiconductor layer, and the first metal film is covered by a semiconductor film such as polysilicon, so when the semiconductor film is planarized using a CMP device during gate formation, it is possible to prevent metal contamination of the CMP device.

In addition, the first gate insulating film and the first metal film are formed only surrounding the first columnar semiconductor layer, and the first metal film is covered by a semiconductor film such as polysilicon, so when the semiconductor film is etched during gate etching, it is possible to prevent metal contamination of the gate etching device.

In addition, the first gate insulating film and the first metal film are formed only surrounding the first columnar semiconductor layer, and the first metal film is covered by a semiconductor film such as polysilicon, so when the nitride film hard mask and the nitride film sidewalls are wet etched, it is possible to prevent metal contamination of the nitride film wet etching device.

[0028] In addition, with the present invention the thickness of the second insulating film is thicker than the sum of the thickness of the first gate insulating film and the thickness of the first metal film.

Through this, the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the

second insulating film, so the first metal film is not etched by the sulfuric acid hydrogen peroxide mixture or the ammonia hydrogen peroxide mixture when the compound of metal and semiconductor is formed. Through this, it is possible to form a metal-semiconductor compound on the first high concentration semiconductor layer, the first gate electrode and the second high concentration semiconductor layer without any special additional processes.

[0029] By having a first metal-semiconductor compound formed on the upper surface of the first high concentration semiconductor layer, it is possible to lower the resistance of the first high concentration semiconductor layer.

[0030] Here, the length from the center of the first columnar semiconductor layer to the edge of the first planar semiconductor layer is larger than the sum of the length from the center to the sidewall of the first columnar semiconductor layer, the thickness of the first gate insulating film, the thickness of the first gate electrode and the thickness of the third insulating film.

Through this, it is possible to form the first metal-semiconductor compound on the first high concentration semiconductor layer formed on the first planar semiconductor layer, and to lower the resistance of the first high concentration semiconductor layer.

[0031] Here, by having a third metal-semiconductor compound formed on the top surface of the first gate electrode, it is possible to lower the resistance of the first gate electrode.

[0032] Here, by having a second metal-semiconductor compound formed on the top surface of the second high concentration semiconductor layer, it is possible to lower the resistance of the second high concentration semiconductor layer.

[0033] The semiconductor device according to a second aspect of the present invention is provided with a first transistor and a second transistor, wherein:

the first transistor has:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer of second conductive type formed on the lower region of the first columnar semiconductor layer and on the region of the first planar

semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of second conductive type formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround upper region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film;

a first metal-semiconductor compound formed on the top surface of the portion of the first high concentration semiconductor layer formed in the region below the first columnar semiconductor layer;

a third metal-semiconductor compound formed on the top surface of the first gate electrode; and,

a second metal-semiconductor compound formed on the top surface of the second high concentration semiconductor layer;

and the second transistor has:

a second planar semiconductor layer;

a second columnar semiconductor layer formed on the second planar semiconductor layer;

a third high concentration semiconductor layer of first conductive type formed on the lower region of the second columnar semiconductor layer and on the region of the second planar semiconductor layer below the second columnar semiconductor layer;

a fourth high concentration semiconductor layer of first conductive type formed on the upper region of the second columnar semiconductor layer;

a second gate insulating film formed on the sidewall of the second columnar semiconductor layer between the third high concentration semiconductor layer and the fourth high concentration semiconductor layer, so as to surround the second columnar semiconductor layer;

a second metal film formed on the second gate insulating film so as to surround the second gate insulating film;

a second semiconductor film formed on the second metal film so as to surround the second metal film;

a second gate electrode composed of the second metal film and the second semiconductor film;

a fourth insulating film formed between the second gate electrode and the second planar semiconductor layer;

a fifth insulating film formed in sidewall shape contacting the upper sidewall of the second columnar semiconductor layer and the top surface of the second gate electrode so as to surround the top region of the second columnar semiconductor layer;

a sixth insulating film formed in a sidewall shape contacting the sidewall of the fourth insulating film and the second gate electrode so as to surround the second gate electrode and the fourth insulating film;

a fourth metal-semiconductor compound formed on the top surface of the portion of the third high concentration semiconductor layer formed in the region below the second columnar

semiconductor layer;

a fifth metal-semiconductor compound formed on the top surface of the second gate electrode; and,

a sixth metal-semiconductor compound formed on the top surface of the fourth high concentration semiconductor layer;

wherein the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film, and

the second gate insulating film and the second metal film are covered by the second columnar semiconductor layer, the second semiconductor film, the fourth insulating film and the fifth insulating film.

Through this, an SGT structure is provided that uses metal in the gate electrode while controlling metal contamination, lowers the resistance of the gate, source and drain, and reduces parasitic capacitance.

The first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film.

If the metal film is exposed when the metal-semiconductor compound is formed, the metal film is etched by a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture when the metal-semiconductor compound is formed. However, in the structure of the present invention, the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film, so the first metal film is not etched by the sulfuric acid hydrogen peroxide mixture or the ammonia hydrogen peroxide mixture when the compound of metal and semiconductor is formed. Through this, it is possible to form a metal-semiconductor compound on the first high concentration semiconductor layer, the first gate electrode and the second high concentration semiconductor layer, and it is possible to control depletion of the channel region

by using metal in the first gate electrode to reduce the resistance of the first gate electrode and to reduce the resistance of the gate, source and drain through a compound of metal and silicon. In addition, it is possible to reduce parasitic capacitance between the first gate electrode and the first planar semiconductor layer by means of the first insulating film.

In addition, the second gate insulating film and the second metal film are covered by the second columnar semiconductor layer, the second semiconductor film, the fourth insulating film and the fifth insulating film. If the metal film is exposed when the metal-semiconductor compound is formed, the metal film is etched by a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture when the metal-semiconductor compound is formed. However, in the structure of the present invention, the second gate insulating film and the second metal film are covered by the second columnar semiconductor layer, the second semiconductor film, the fourth insulating film and the fifth insulating film, so the second metal film is not etched by the sulfuric acid hydrogen peroxide mixture or the ammonia hydrogen peroxide mixture when the metal-semiconductor compound is formed. Through this, it is possible to form a metal-semiconductor compound on the third high concentration semiconductor layer, the second gate electrode and the fourth high concentration semiconductor layer, to control depletion of the channel region by using metal in the second gate electrode, to reduce the resistance of the second gate electrode and to reduce the resistance of the gate, source and drain through a compound of metal and silicon. In addition, it is possible to reduce parasitic capacitance between the second gate electrode and the second planar semiconductor layer by means of the fourth insulating film.

[0034] Here, the first gate insulating film and the first metal film are formed from materials that make the first transistor enhancement-type, and

the second gate insulating film and the second metal film are formed from materials that make the second transistor enhancement-type.

Through this, it is possible to reduce penetrating current that flows during operation of a semiconductor device composed of a first transistor and a second transistor.

[0035] Here, by having the thickness of the second insulating film be thicker than the sum of the thickness of the first gate insulating film and the thickness of the first metal film, the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film, so the first metal film is not etched by the sulfuric acid hydrogen peroxide mixture or the ammonia hydrogen peroxide mixture when the compound of metal and semiconductor is formed.

Through this, it is possible to form a metal-semiconductor compound on the third high concentration semiconductor layer, the first gate electrode and the fourth high concentration semiconductor layer.

[0036] Here, by having the length from the center of the first columnar semiconductor layer to the edge of the first planar semiconductor layer be larger than the sum of the length from the center to the sidewall of the first columnar semiconductor layer, the thickness of the first gate insulating film, the thickness of the first gate electrode and the thickness of the third insulating film, it is possible to form the first metal-semiconductor compound on the third high concentration semiconductor layer formed on the first planar semiconductor layer, and to lower the resistance of the third high concentration semiconductor layer.

[0037] It is also possible for the semiconductor device to be such that:

the first conductive type is n+ type,

the second conductive type is p+ type, and

the first and second columnar semiconductor layers and the first and second planar semiconductor layers are made of silicon.

Through this, it is possible to form an inverter with the first transistor being an nMOS SGT and the second transistor being a pMOS SGT.

[0038] The method of producing a semiconductor device according to the present invention includes:

a process for preparing a first structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer and a hard mask formed on the top surface of the first columnar semiconductor;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer; and

a first insulating film formed on the first planar semiconductor layer;

a process for forming a seventh insulating film, a third metal film and a third semiconductor film, in that order, on the first structure;

a process for etching the third semiconductor film and leaving a sidewall shape on the sidewall on the first columnar semiconductor layer;

a process for etching the third metal film and leaving a sidewall shape on the sidewall of the first columnar semiconductor layer;

a seventh insulating film etching process for etching the seventh insulating film and leaving a sidewall shape on the sidewall of the first columnar semiconductor layer; and

a fourth semiconductor film formation process for forming a fourth semiconductor film on the result of the seventh insulating film etching process.

Through this, the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the hard mask. When a high-k film is used for the first gate insulating film, the high-k film is a source of metal contamination, so it is possible to control metal contamination by the first gate insulating film and the first metal film, which are sources of contamination, being covered by the first columnar semiconductor layer, the fourth semiconductor film, the first insulating film and the hard mask.

[0039] In addition, the semiconductor device production method according to the present invention may include:

a process for planarizing the fourth semiconductor film and the third semiconductor film in the result of the fourth semiconductor film formation process and exposing the upper region of

the first metal film;

a first metal film and first gate insulating film formation process for etching the third metal film and the seventh insulating film so that the upper sidewall of the first columnar semiconductor layer is exposed to form the first metal film and the first gate insulating film; and,

a process for forming a first oxide film on the result of the first metal film and first gate insulating film formation process.

Through this, it is possible to control metal contamination of the CMP device used in the planarization process because metal is not exposed during the process of planarizing the fourth semiconductor film and the third semiconductor film, it is possible to determine the gate length of the SGT through etching of the semiconductor film, and it is possible to control fluctuations in gate length, that is to say variances in gate length, and damage to the first gate insulating film and the first metal film from the gate electrode top surface because the gate electrode top surface is protected by the deposited first oxide film from wet processes and dry processes performed in later procedures.

In addition, the first gate insulating film and the first metal film are formed only around the first columnar silicon layer and the first metal film is covered by polysilicon, so it is possible to reduce metal contamination of the gate etching device by etching the polysilicon during gate etching.

In addition, the first gate insulating film and the first metal film are formed only around the columnar semiconductor layer and the first metal film is covered by the first columnar semiconductor layer and the third and fourth semiconductor films, so it is possible to reduce metal contamination of the nitride film wet etching device when wet etching the nitride film hard mask and the nitride film sidewall.

[0040] In addition, the method of producing a semiconductor device according to the present invention includes:

a process for preparing a second structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall in the middle region of the first columnar semiconductor layer so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film; and

a first insulating film formed between the first gate electrode and the first planar semiconductor layer; and

a process for forming a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer on the upper region of the first columnar semiconductor layer on the second structure by injecting a dopant at an angle of 10 degrees to 60 degrees, with a line orthogonal to the substrate being 0 degrees.

Through this, it is possible to cover the first gate insulating film and the first metal film with the first columnar semiconductor layer, the first semiconductor layer, the first insulating film and the second insulating film.

[0041] In addition, the method of producing a semiconductor device according to the present invention includes:

a process for preparing a third structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below

the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film; and

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a process for forming an eighth insulating film on the third structure; and

a process for forming a second insulating film by etching the eighth insulating film in a sidewall shape so the eighth insulating film remains on the top surface of the first gate electrode and the upper sidewall of the first columnar semiconductor layer.

Through this, it is possible for the second high concentration silicon layer and the first gate electrode to be separated from the first gate insulating film, to have an overlap and to minimize that overlap.

[0042] In addition, the method of producing a semiconductor device according to the present invention includes:

a process for preparing a fourth structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first

columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround the top region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film; and

a first gate wire connected to the first gate electrode;

a contact stopper formation process for forming a contact stopper on the fourth structure;

a process for forming an interlayer insulating film so as to bury the result of the contact stopper formation process;

a process for forming a first resist on the interlayer insulating film, excluding on top of the first columnar semiconductor layer;

a process for etching the interlayer insulating film and forming a first contact hole on the interlayer insulating film;

a first resist removal process for removing the first resist;

a process for forming a second resist on the result of the first resist removal process, excluding on the first planar semiconductor layer and on the first gate wire;

a process for etching the interlayer insulating film and forming a second contact hole on top of the first planar semiconductor layer and forming a third contact hole on top of the first gate wire, on the interlayer insulating film;

a process for removing the second resist; and

a process for forming a first contact positioned above the first columnar semiconductor layer, a second contact positioned above the first planar semiconductor layer and a third contact positioned above the first gate wire on the first contact hole, the second contact hole and the third contact hole, respectively.

Through this, the contact holes on the first planar semiconductor layer and the first gate wiring are formed through different processes, so it is possible to optimize etching conditions for forming the first contact hole on the first columnar semiconductor layer and etching conditions for forming the second contact hole on the first planar semiconductor layer and the third contact hole on the first gate wiring.

BRIEF DESCRIPTION OF THE DRAWINGS

[0043] A more complete understanding of this application can be obtained when the following detailed description is considered in conjunction with the following drawings, in which:

FIG. 1A is a planar view of the semiconductor device according to an embodiment of the present invention;

FIG. 1B is a cross-sectional view along line X-X' in FIG. 1A;

FIG. 1C is a cross-sectional view along line Y1-Y1' in FIG. 1A;

FIG. 1D is a cross-sectional view along line Y2-Y2' in FIG. 1A;

FIG. 2A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 2B is a cross-sectional view along line X-X' in FIG. 2A;

FIG. 2C is a cross-sectional view along line Y1-Y1' in FIG. 2A;

FIG. 2D is a cross-sectional view along line Y2-Y2' in FIG. 2A;

FIG. 3A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 3B is a cross-sectional view along line X-X' in FIG. 3A;

FIG. 3C is a cross-sectional view along line Y1-Y1' in FIG. 3A;

FIG. 3D is a cross-sectional view along line Y2-Y2' in FIG. 3A;

FIG. 4A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 4B is a cross-sectional view along line X-X' in FIG. 4A;

FIG. 4C is a cross-sectional view along line Y1-Y1' in FIG. 4A;

FIG. 4D is a cross-sectional view along line Y2-Y2' in FIG. 4A;

FIG. 5A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 5B is a cross-sectional view along line X-X' in FIG. 5A;

FIG. 5C is a cross-sectional view along line Y1-Y1' in FIG. 5A;

FIG. 5D is a cross-sectional view along line Y2-Y2' in FIG. 5A;

FIG. 6A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 6B is a cross-sectional view along line X-X' in FIG. 6A;

FIG. 6C is a cross-sectional view along line Y1-Y1' in FIG. 6A;

FIG. 6D is a cross-sectional view along line Y2-Y2' in FIG. 6A;

FIG. 7A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 7B is a cross-sectional view along line X-X' in FIG. 7A;

FIG. 7C is a cross-sectional view along line Y1-Y1' in FIG. 7A;

FIG. 7D is a cross-sectional view along line Y2-Y2' in FIG. 7A;

FIG. 8A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 8B is a cross-sectional view along line X-X' in FIG. 8A;

FIG. 8C is a cross-sectional view along line Y1-Y1' in FIG. 8A;

FIG. 8D is a cross-sectional view along line Y2-Y2' in FIG. 8A;

FIG. 9A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 9B is a cross-sectional view along line X-X' in FIG. 9A;

FIG. 9C is a cross-sectional view along line Y1-Y1' in FIG. 9A;

FIG. 9D is a cross-sectional view along line Y2-Y2' in FIG. 9A;

FIG. 10A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 10B is a cross-sectional view along line X-X' in FIG. 10A;

FIG. 10C is a cross-sectional view along line Y1-Y1' in FIG. 10A;

FIG. 10D is a cross-sectional view along line Y2-Y2' in FIG. 10A;

FIG. 11A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 11B is a cross-sectional view along line X-X' in FIG. 11A;

FIG. 11C is a cross-sectional view along line Y1-Y1' in FIG. 11A;

FIG. 11D is a cross-sectional view along line Y2-Y2' in FIG. 11A;

FIG. 12A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 12B is a cross-sectional view along line X-X' in FIG. 12A;

FIG. 12C is a cross-sectional view along line Y1-Y1' in FIG. 12A;

FIG. 12D is a cross-sectional view along line Y2-Y2' in FIG. 12A;

FIG. 13A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 13B is a cross-sectional view along line X-X' in FIG. 13A;

FIG. 13C is a cross-sectional view along line Y1-Y1' in FIG. 13A;

FIG. 13D is a cross-sectional view along line Y2-Y2' in FIG. 13A;

FIG. 14A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 14B is a cross-sectional view along line X-X' in FIG. 14A;

FIG. 14C is a cross-sectional view along line Y1-Y1' in FIG. 14A;

FIG. 14D is a cross-sectional view along line Y2-Y2' in FIG. 14A;

FIG. 15A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 15B is a cross-sectional view along line X-X' in FIG. 15A;

FIG. 15C is a cross-sectional view along line Y1-Y1' in FIG. 15A;

FIG. 15D is a cross-sectional view along line Y2-Y2' in FIG. 15A;

FIG. 16A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 16B is a cross-sectional view along line X-X' in FIG. 16A;

FIG. 16C is a cross-sectional view along line Y1-Y1' in FIG. 16A;

FIG. 16D is a cross-sectional view along line Y2-Y2' in FIG. 16A;

FIG. 17A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 17B is a cross-sectional view along line X-X' in FIG. 17A;

FIG. 17C is a cross-sectional view along line Y1-Y1' in FIG. 17A;

FIG. 17D is a cross-sectional view along line Y2-Y2' in FIG. 17A;

FIG. 18A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 18B is a cross-sectional view along line X-X' in FIG. 18A;

FIG. 18C is a cross-sectional view along line Y1-Y1' in FIG. 18A;

FIG. 18D is a cross-sectional view along line Y2-Y2' in FIG. 18A;

FIG. 19A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 19B is a cross-sectional view along line X-X' in FIG. 19A;

FIG. 19C is a cross-sectional view along line Y1-Y1' in FIG. 19A;

FIG. 19D is a cross-sectional view along line Y2-Y2' in FIG. 19A;

FIG. 20A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 20B is a cross-sectional view along line X-X' in FIG. 20A;

FIG. 20C is a cross-sectional view along line Y1-Y1' in FIG. 20A;

FIG. 20D is a cross-sectional view along line Y2-Y2' in FIG. 20A;

FIG. 21A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 21B is a cross-sectional view along line X-X' in FIG. 21A;

FIG. 21C is a cross-sectional view along line Y1-Y1' in FIG. 21A;

FIG. 21D is a cross-sectional view along line Y2-Y2' in FIG. 21A;

FIG. 22A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 22B is a cross-sectional view along line X-X' in FIG. 22A;

FIG. 22C is a cross-sectional view along line Y1-Y1' in FIG. 22A;

FIG. 22D is a cross-sectional view along line Y2-Y2' in FIG. 22A;

FIG. 23A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 23B is a cross-sectional view along line X-X' in FIG. 23A;

FIG. 23C is a cross-sectional view along line Y1-Y1' in FIG. 23A;

FIG. 23D is a cross-sectional view along line Y2-Y2' in FIG. 23A;

FIG. 24A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 24B is a cross-sectional view along line X-X' in FIG. 24A;

FIG. 24C is a cross-sectional view along line Y1-Y1' in FIG. 24A;

FIG. 24D is a cross-sectional view along line Y2-Y2' in FIG. 24A;

FIG. 25A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 25B is a cross-sectional view along line X-X' in FIG. 25A;

FIG. 25C is a cross-sectional view along line Y1-Y1' in FIG. 25A;

FIG. 25D is a cross-sectional view along line Y2-Y2' in FIG. 25A;

FIG. 26A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 26B is a cross-sectional view along line X-X' in FIG. 26A;

FIG. 26C is a cross-sectional view along line Y1-Y1' in FIG. 26A;

FIG. 26D is a cross-sectional view along line Y2-Y2' in FIG. 26A;

FIG. 27A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 27B is a cross-sectional view along line X-X' in FIG. 27A;

FIG. 27C is a cross-sectional view along line Y1-Y1' in FIG. 27A;

FIG. 27D is a cross-sectional view along line Y2-Y2' in FIG. 27A;

FIG. 28A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 28B is a cross-sectional view along line X-X' in FIG. 28A;

FIG. 28C is a cross-sectional view along line Y1-Y1' in FIG. 28A;

FIG. 28D is a cross-sectional view along line Y2-Y2' in FIG. 28A;

FIG. 29A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 29B is a cross-sectional view along line X-X' in FIG. 29A;

FIG. 29C is a cross-sectional view along line Y1-Y1' in FIG. 29A;

FIG. 29D is a cross-sectional view along line Y2-Y2' in FIG. 29A;

FIG. 30A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 30B is a cross-sectional view along line X-X' in FIG. 30A;

FIG. 30C is a cross-sectional view along line Y1-Y1' in FIG. 30A;

FIG. 30D is a cross-sectional view along line Y2-Y2' in FIG. 30A;

FIG. 31A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 31B is a cross-sectional view along line X-X' in FIG. 31A;

FIG. 31C is a cross-sectional view along line Y1-Y1' in FIG. 31A;

FIG. 31D is a cross-sectional view along line Y2-Y2' in FIG. 31A;

FIG. 32A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 32B is a cross-sectional view along line X-X' in FIG. 32A;

FIG. 32C is a cross-sectional view along line Y1-Y1' in FIG. 32A;

FIG. 32D is a cross-sectional view along line Y2-Y2' in FIG. 32A;

FIG. 33A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 33B is a cross-sectional view along line X-X' in FIG. 33A;

FIG. 33C is a cross-sectional view along line Y1-Y1' in FIG. 33A;

FIG. 33D is a cross-sectional view along line Y2-Y2' in FIG. 33A;

FIG. 34A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 34B is a cross-sectional view along line X-X' in FIG. 34A;

FIG. 34C is a cross-sectional view along line Y1-Y1' in FIG. 34A;

FIG. 34D is a cross-sectional view along line Y2-Y2' in FIG. 34A;

FIG. 35A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 35B is a cross-sectional view along line X-X' in FIG. 35A;

FIG. 35C is a cross-sectional view along line Y1-Y1' in FIG. 35A;

FIG. 35D is a cross-sectional view along line Y2-Y2' in FIG. 35A;

FIG. 36A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 36B is a cross-sectional view along line X-X' in FIG. 36A;

FIG. 36C is a cross-sectional view along line Y1-Y1' in FIG. 36A;

FIG. 36D is a cross-sectional view along line Y2-Y2' in FIG. 36A;

FIG. 37A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 37B is a cross-sectional view along line X-X' in FIG. 37A;

FIG. 37C is a cross-sectional view along line Y1-Y1' in FIG. 37A;

FIG. 37D is a cross-sectional view along line Y2-Y2' in FIG. 37A;

FIG. 38A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 38B is a cross-sectional view along line X-X' in FIG. 38A;

FIG. 38C is a cross-sectional view along line Y1-Y1' in FIG. 38A;

FIG. 38D is a cross-sectional view along line Y2-Y2' in FIG. 38A;

FIG. 39A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 39B is a cross-sectional view along line X-X' in FIG. 39A;

FIG. 39C is a cross-sectional view along line Y1-Y1' in FIG. 39A;

FIG. 39D is a cross-sectional view along line Y2-Y2' in FIG. 39A;

FIG. 40A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 40B is a cross-sectional view along line X-X' in FIG. 40A;

FIG. 40C is a cross-sectional view along line Y1-Y1' in FIG. 40A;

FIG. 40D is a cross-sectional view along line Y2-Y2' in FIG. 40A;

FIG. 41A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 41B is a cross-sectional view along line X-X' in FIG. 41A;

FIG. 41C is a cross-sectional view along line Y1-Y1' in FIG. 41A;

FIG. 41D is a cross-sectional view along line Y2-Y2' in FIG. 41A;

FIG. 42A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 42B is a cross-sectional view along line X-X' in FIG. 42A;

FIG. 42C is a cross-sectional view along line Y1-Y1' in FIG. 42A;

FIG. 42D is a cross-sectional view along line Y2-Y2' in FIG. 42A;

FIG. 43A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 43B is a cross-sectional view along line X-X' in FIG. 43A;

FIG. 43C is a cross-sectional view along line Y1-Y1' in FIG. 43A;

FIG. 43D is a cross-sectional view along line Y2-Y2' in FIG. 43A;

FIG. 44A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 44B is a cross-sectional view along line X-X' in FIG. 44A;

FIG. 44C is a cross-sectional view along line Y1-Y1' in FIG. 44A;

FIG. 44D is a cross-sectional view along line Y2-Y2' in FIG. 44A;

FIG. 45A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 45B is a cross-sectional view along line X-X' in FIG. 45A;

FIG. 45C is a cross-sectional view along line Y1-Y1' in FIG. 45A;

FIG. 45D is a cross-sectional view along line Y2-Y2' in FIG. 45A;

FIG. 46A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 46B is a cross-sectional view along line X-X' in FIG. 46A;

FIG. 46C is a cross-sectional view along line Y1-Y1' in FIG. 46A;

FIG. 46D is a cross-sectional view along line Y2-Y2' in FIG. 46A;

FIG. 47A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 47B is a cross-sectional view along line X-X' in FIG. 47A;

FIG. 47C is a cross-sectional view along line Y1-Y1' in FIG. 47A;

FIG. 47D is a cross-sectional view along line Y2-Y2' in FIG. 47A;

FIG. 48A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 48B is a cross-sectional view along line X-X' in FIG. 48A;

FIG. 48C is a cross-sectional view along line Y1-Y1' in FIG. 48A;

FIG. 48D is a cross-sectional view along line Y2-Y2' in FIG. 48A;

FIG. 49A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 49B is a cross-sectional view along line X-X' in FIG. 49A;

FIG. 49C is a cross-sectional view along line Y1-Y1' in FIG. 49A;

FIG. 49D is a cross-sectional view along line Y2-Y2' in FIG. 49A;

FIG. 50A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 50B is a cross-sectional view along line X-X' in FIG. 50A;

FIG. 50C is a cross-sectional view along line Y1-Y1' in FIG. 50A;

FIG. 50D is a cross-sectional view along line Y2-Y2' in FIG. 50A;

FIG. 51A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 51B is a cross-sectional view along line X-X' in FIG. 51A;

FIG. 51C is a cross-sectional view along line Y1-Y1' in FIG. 51A;

FIG. 51D is a cross-sectional view along line Y2-Y2' in FIG. 51A;

FIG. 52A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 52B is a cross-sectional view along line X-X' in FIG. 52A;

FIG. 52C is a cross-sectional view along line Y1-Y1' in FIG. 52A;

FIG. 52D is a cross-sectional view along line Y2-Y2' in FIG. 52A;

FIG. 53A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 53B is a cross-sectional view along line X-X' in FIG. 53A;

FIG. 53C is a cross-sectional view along line Y1-Y1' in FIG. 53A;

FIG. 53D is a cross-sectional view along line Y2-Y2' in FIG. 53A;

FIG. 54A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 54B is a cross-sectional view along line X-X' in FIG. 54A;

FIG. 54C is a cross-sectional view along line Y1-Y1' in FIG. 54A;

FIG. 54D is a cross-sectional view along line Y2-Y2' in FIG. 54A;

FIG. 55A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 55B is a cross-sectional view along line X-X' in FIG. 55A;

FIG. 55C is a cross-sectional view along line Y1-Y1' in FIG. 55A;

FIG. 55D is a cross-sectional view along line Y2-Y2' in FIG. 55A;

FIG. 56A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 56B is a cross-sectional view along line X-X' in FIG. 56A;

FIG. 56C is a cross-sectional view along line Y1-Y1' in FIG. 56A;

FIG. 56D is a cross-sectional view along line Y2-Y2' in FIG. 56A;

FIG. 57A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 57B is a cross-sectional view along line X-X' in FIG. 57A;

FIG. 57C is a cross-sectional view along line Y1-Y1' in FIG. 57A;

FIG. 57D is a cross-sectional view along line Y2-Y2' in FIG. 57A;

FIG. 58A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 58B is a cross-sectional view along line X-X' in FIG. 58A;

FIG. 58C is a cross-sectional view along line Y1-Y1' in FIG. 58A;

FIG. 58D is a cross-sectional view along line Y2-Y2' in FIG. 58A;

FIG. 59A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 59B is a cross-sectional view along line X-X' in FIG. 59A;

FIG. 59C is a cross-sectional view along line Y1-Y1' in FIG. 59A;

FIG. 59D is a cross-sectional view along line Y2-Y2' in FIG. 59A;

FIG. 60A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 60B is a cross-sectional view along line X-X' in FIG. 60A;

FIG. 60C is a cross-sectional view along line Y1-Y1' in FIG. 60A;

FIG. 60D is a cross-sectional view along line Y2-Y2' in FIG. 60A;

FIG. 61A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 61B is a cross-sectional view along line X-X' in FIG. 61A;

FIG. 61C is a cross-sectional view along line Y1-Y1' in FIG. 61A;

FIG. 61D is a cross-sectional view along line Y2-Y2' in FIG. 61A;

FIG. 62A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 62B is a cross-sectional view along line X-X' in FIG. 62A;

FIG. 62C is a cross-sectional view along line Y1-Y1' in FIG. 62A;

FIG. 62D is a cross-sectional view along line Y2-Y2' in FIG. 62A;

FIG. 63A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 63B is a cross-sectional view along line X-X' in FIG. 63A;

FIG. 63C is a cross-sectional view along line Y1-Y1' in FIG. 63A;

FIG. 63D is a cross-sectional view along line Y2-Y2' in FIG. 63A;

FIG. 64A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 64B is a cross-sectional view along line X-X' in FIG. 64A;

FIG. 64C is a cross-sectional view along line Y1-Y1' in FIG. 64A;

FIG. 64D is a cross-sectional view along line Y2-Y2' in FIG. 64A;

FIG. 65A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 65B is a cross-sectional view along line X-X' in FIG. 65A;

FIG. 65C is a cross-sectional view along line Y1-Y1' in FIG. 65A;

FIG. 65D is a cross-sectional view along line Y2-Y2' in FIG. 65A;

FIG. 66A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 66B is a cross-sectional view along line X-X' in FIG. 66A;

FIG. 66C is a cross-sectional view along line Y1-Y1' in FIG. 66A;

FIG. 66D is a cross-sectional view along line Y2-Y2' in FIG. 66A;

FIG. 67A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 67B is a cross-sectional view along line X-X' in FIG. 67A;

FIG. 67C is a cross-sectional view along line Y1-Y1' in FIG. 67A;

FIG. 67D is a cross-sectional view along line Y2-Y2' in FIG. 67A;

FIG. 68A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 68B is a cross-sectional view along line X-X' in FIG. 68A;

FIG. 68C is a cross-sectional view along line Y1-Y1' in FIG. 68A;

FIG. 68D is a cross-sectional view along line Y2-Y2' in FIG. 68A;

FIG. 69A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 69B is a cross-sectional view along line X-X' in FIG. 69A;

FIG. 69C is a cross-sectional view along line Y1-Y1' in FIG. 69A;

FIG. 69D is a cross-sectional view along line Y2-Y2' in FIG. 69A;

FIG. 70A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 70B is a cross-sectional view along line X-X' in FIG. 70A;

FIG. 70C is a cross-sectional view along line Y1-Y1' in FIG. 70A;

FIG. 70D is a cross-sectional view along line Y2-Y2' in FIG. 70A;

FIG. 71A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 71B is a cross-sectional view along line X-X' in FIG. 71A;

FIG. 71C is a cross-sectional view along line Y1-Y1' in FIG. 71A;

FIG. 71D is a cross-sectional view along line Y2-Y2' in FIG. 71A;

FIG. 72A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 72B is a cross-sectional view along line X-X' in FIG. 72A;

FIG. 72C is a cross-sectional view along line Y1-Y1' in FIG. 72A;

FIG. 72D is a cross-sectional view along line Y2-Y2' in FIG. 72A;

FIG. 73A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 73B is a cross-sectional view along line X-X' in FIG. 73A;

FIG. 73C is a cross-sectional view along line Y1-Y1' in FIG. 73A;

FIG. 73D is a cross-sectional view along line Y2-Y2' in FIG. 73A;

FIG. 74A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 74B is a cross-sectional view along line X-X' in FIG. 74A;

FIG. 74C is a cross-sectional view along line Y1-Y1' in FIG. 74A;

FIG. 74D is a cross-sectional view along line Y2-Y2' in FIG. 74A;

FIG. 75A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 75B is a cross-sectional view along line X-X' in FIG. 75A;

FIG. 75C is a cross-sectional view along line Y1-Y1' in FIG. 75A;

FIG. 75D is a cross-sectional view along line Y2-Y2' in FIG. 75A;

FIG. 76A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 76B is a cross-sectional view along line X-X' in FIG. 76A;

FIG. 76C is a cross-sectional view along line Y1-Y1' in FIG. 76A;

FIG. 76D is a cross-sectional view along line Y2-Y2' in FIG. 76A;

FIG. 77A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 77B is a cross-sectional view along line X-X' in FIG. 77A;

FIG. 77C is a cross-sectional view along line Y1-Y1' in FIG. 77A;

FIG. 77D is a cross-sectional view along line Y2-Y2' in FIG. 77A;

FIG. 78A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 78B is a cross-sectional view along line X-X' in FIG. 78A;

FIG. 78C is a cross-sectional view along line Y1-Y1' in FIG. 78A;

FIG. 78D is a cross-sectional view along line Y2-Y2' in FIG. 78A;

FIG. 79A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 79B is a cross-sectional view along line X-X' in FIG. 79A;

FIG. 79C is a cross-sectional view along line Y1-Y1' in FIG. 79A;

FIG. 79D is a cross-sectional view along line Y2-Y2' in FIG. 79A;

FIG. 80A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 80B is a cross-sectional view along line X-X' in FIG. 80A;

FIG. 80C is a cross-sectional view along line Y1-Y1' in FIG. 80A;

FIG. 80D is a cross-sectional view along line Y2-Y2' in FIG. 80A;

FIG. 81A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 81B is a cross-sectional view along line X-X' in FIG. 81A;

FIG. 81C is a cross-sectional view along line Y1-Y1' in FIG. 81A;

FIG. 81D is a cross-sectional view along line Y2-Y2' in FIG. 81A;

FIG. 82A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 82B is a cross-sectional view along line X-X' in FIG. 82A;

FIG. 82C is a cross-sectional view along line Y1-Y1' in FIG. 82A;

FIG. 82D is a cross-sectional view along line Y2-Y2' in FIG. 82A;

FIG. 83A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 83B is a cross-sectional view along line X-X' in FIG. 83A;

FIG. 83C is a cross-sectional view along line Y1-Y1' in FIG. 83A;

FIG. 83D is a cross-sectional view along line Y2-Y2' in FIG. 83A;

FIG. 84A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 84B is a cross-sectional view along line X-X' in FIG. 84A;

FIG. 84C is a cross-sectional view along line Y1-Y1' in FIG. 84A;

FIG. 84D is a cross-sectional view along line Y2-Y2' in FIG. 84A;

FIG. 85A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 85B is a cross-sectional view along line X-X' in FIG. 85A;

FIG. 85C is a cross-sectional view along line Y1-Y1' in FIG. 85A;

FIG. 85D is a cross-sectional view along line Y2-Y2' in FIG. 85A;

FIG. 86A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 86B is a cross-sectional view along line X-X' in FIG. 86A;

FIG. 86C is a cross-sectional view along line Y1-Y1' in FIG. 86A;

FIG. 86D is a cross-sectional view along line Y2-Y2' in FIG. 86A;

FIG. 87A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present

invention;

FIG. 87B is a cross-sectional view along line X-X' in FIG. 87A;

FIG. 87C is a cross-sectional view along line Y1-Y1' in FIG. 87A;

FIG. 87D is a cross-sectional view along line Y2-Y2' in FIG. 87A;

FIG. 88A is a planar view of the semiconductor device during production, showing the method of producing the semiconductor device according to an embodiment of the present invention;

FIG. 88B is a cross-sectional view along line X-X' in FIG. 88A;

FIG. 88C is a cross-sectional view along line Y1-Y1' in FIG. 88A; and

FIG. 88D is a cross-sectional view along line Y2-Y2' in FIG. 88A;

DETAILED DESCRIPTION

[0044] The embodiments of the present invention are described below with reference to FIGS. 1A to 88D.

[0045] (Embodiment 1)

FIG. 1C shows an SGT **220** according to a first embodiment of the present invention.

[0046] This SGT **220** is an nMOS SGT and is provided with a first planar silicon layer **234** and a first columnar silicon layer **232** formed on top of the first planar silicon layer **234**.

[0047] A first n+ type silicon layer **113** is formed on the lower region of the first columnar silicon layer **232** and the region of the first planar silicon layer **234** positioned below the first columnar silicon layer **232**, and a second n+ type silicon layer **157** is formed on the upper region of the first columnar silicon layer **232**. In this embodiment, the first n+ type silicon layer **113**, for example, functions as a source scattering layer and the second n+ type silicon layer **157** functions as a drain scattering layer. In addition, the area between the source scattering layer and the drawing scattering layer functions as a channel region. The first columnar silicon layer **232** between the first n+ type silicon layer **113** and the second n+ type silicon layer **157** functioning as this channel region is called a first silicon layer **114**.

[0048] A gate insulating film **140** is formed surrounding the first columnar silicon layer **232**

functioning as the channel region. The gate insulating film **140** may be, for example, an oxide film, a nitride film or a high-k film. Furthermore, a first metal film **138** is formed surrounding this gate insulating film **140**. The first metal film **138** may be, for example, titanium, titanium nitride, tantalum or tantalum nitride. First polysilicon films **136** and **152** are formed surrounding this first metal film **138**. The first metal film **138** and the first polysilicon films **136** and **152** constitute a first gate electrode **236**. Thus, by using metal as the gate electrode, it is possible to control depletion of the channel region while also lowering the resistance of the gate electrode.

In the present embodiment, a channel is formed in the first silicon layer **114** by impressing a voltage on the first gate electrode **236** during operation.

[0049] In addition, a first metal-silicon compound **172**, a third metal-silicon compound **170** and a second metal-silicon compound **171** are formed on the first n+ type silicon layer **113**, the gate electrode **236** and the second n+ type silicon layer **157**, respectively. As the metal comprising the metal-silicon compounds, Ni or Co may be used, for example. Through these metal-silicon compounds, the first n+ type silicon layer **113**, the gate electrode **236** and the second n+ type silicon layer **157** are connected to below-described contacts. Through this, the resistances of the gate, source and drain are lowered.

[0050] The first n+ type silicon layer **113** is connected to a contact **230** via the first metal-silicon compound **172**. The contact **230** is formed from a barrier metal layer **189** and metal layers **194** and **199**. The contact **230** is further connected to a power source wire **225**. The power source wire **225** is composed of a barrier metal layer **216**, a metal layer **217** and a barrier metal layer **218**.

[0051] The second n+ type silicon layer **157** is connected to a contact **229** via the second metal-silicon compound **171**. The contact **229** is composed of a barrier metal layer **188** and metal layers **193** and **198**. The contact **229** is further connected to an output wire **223**. The output wire **223** is composed of a barrier metal layer **213**, a metal **214** and a barrier metal layer **215**.

[0052] Furthermore, a first insulating film **129** is formed between the first gate electrode **236**

and the first planar silicon layer **234**, a second insulating film **162** is formed in a sidewall shape on the upper sidewall of the first columnar silicon layer **232** and above the first gate electrode **236**, and a third insulating film **164** is formed in a sidewall shape on the sidewall of the first gate electrode **236** and the first insulating film **129**. The first insulating film **129** is preferably a low-k insulating film such as SiOF, SiOH or the like, for example. The second insulating film **162** and the third insulating film **164** are oxide films, nitride films or high-k films, for example.

The parasitic capacitance between the gate electrode and the planar silicon layer is reduced by the first insulating film **129**.

[0053] With the above composition, downsizing and lowering of resistance in the semiconductor device are realized in the nMOS SGT according to the present embodiment, and in addition parasitic capacitance between multi-layer wiring is reduced. Through this, it is possible to avoid lowering of operation speeds accompanying downsizing of the SGT.

[0054] In the nMOS SGT according to this embodiment, the thickness of the second insulating film **162** is preferably thicker than the sum of the thickness of the first gate insulating film **140** and the thickness of the first metal film **138**. In this case, the first gate insulating film **140** and the first metal film **138** are covered by the first columnar silicon layer **232**, the first polysilicon films **136** and **152**, the first insulating film **129** and the second insulating film **162**.

By using the above-described composition, the entirety of the first metal film **138** is protected, so this film is not etched by a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture when forming the metal-silicon compound.

[0055] In addition, the length from the center of the first columnar silicon layer **232** to the end of the first planar silicon layer **234** in the nMOS SGT according to the present embodiment is preferably larger than the sum of the length from the center to the sidewall of the first columnar silicon layer **232**, the thickness of the first gate insulating film **140**, the thickness of the first gate electrode **236** formed by the first metal film **138** and the first polysilicon films **136** and **152** and the thickness of the third insulating film **164**.

When the above-described composition is used, it is possible to form the first metal-

silicon compound **172** on the first n+ type silicon layer **113** without the special addition of manufacturing processes.

[0056] (Embodiment 2)

In the first embodiment, an example was shown of a single columnar semiconductor layer, but in the second embodiment, an example is shown of a circuit composed of multiple columnar semiconductor layers.

An inverter according to the second embodiment is provided with a pMOS SGT and an nMOS SGT.

[0057] The nMOS SGT **220** is provided with a first planar silicon layer **234** and a first columnar silicon layer **232** formed on top of the first planar silicon layer **234**.

[0058] A first n+ type silicon layer **113** is formed on the lower region of the first columnar silicon layer **232** and the region of the first planar silicon layer **234** positioned below the first columnar silicon layer **232**, and a second n+ type silicon layer **157** is formed on the upper region of the first columnar silicon layer **232**. In this embodiment, the first n+ type silicon layer **113**, for example, functions as a source scattering layer and the second n+ type silicon layer **157** functions as a drain scattering layer. In addition, the area between the source scattering layer and the drawing scattering layer functions as a channel region. The first columnar silicon layer **232** between the first n+ type silicon layer **113** and the second n+ type silicon layer **157** functioning as this channel region is called a first silicon layer **114**.

[0059] A first gate insulating film **140** is formed surrounding the first columnar silicon layer **232** functioning as the channel region. The gate insulating film **140** may be, for example, an oxide film, a nitride film or a high-k film. Furthermore, a first metal film **138** is formed surrounding this first gate insulating film **140**. The first metal film **138** may be, for example, titanium, titanium nitride, tantalum or tantalum nitride. First polysilicon films **136** and **152** are formed surrounding this first metal film **138**. The first metal film **138** and the first polysilicon films **136** and **152** constitute a first gate electrode **236**. Thus, by using metal as the gate electrode, it is possible to control depletion of the channel region while also lowering the

resistance of the gate electrode.

In the present embodiment, a channel is formed in the first silicon layer **114** by impressing a voltage on the first gate electrode **236** during operation.

[0060] In addition, a first metal-silicon compound **172**, a third metal-silicon compound **170** and a second metal-silicon compound **171** are formed on the first n+ type silicon layer **113**, the first gate electrode **236** and the second n+ type silicon layer **157**, respectively. The metal comprising the metal-silicon compounds may be Ni or Co, for example. Through these metal-silicon compounds, the first n+ type silicon layer **113**, the gate electrode **236** and the second n+ type silicon layer **157** are connected to below-described contacts. Through this, the resistances of the gate, source and drain are lowered.

[0061] Furthermore, a first insulating film **129** is formed between the first gate electrode **236** and the first planar silicon layer **234**, a second insulating film **162** is formed in a sidewall shape on the upper sidewall of the first columnar silicon layer **232** and above the first gate electrode **236**, and a third insulating film **164** is formed in a sidewall shape on the sidewall of the first gate electrode **236** and the first insulating film **129**. The first insulating film **129** is preferably a low-k insulating film such as SiOF, SiOH or the like, for example. The second insulating film **162** and the third insulating film **164** are oxide films, nitride films or high-k films, for example.

The parasitic capacitance between the gate electrode and the planar silicon layer is reduced by the first insulating film **129**.

[0062] The pMOS SGT **219** and is provided with a second planar silicon layer **233** and a second columnar silicon layer **231** formed on top of the second planar silicon layer **233**.

[0063] A first p+ type silicon layer **119** is formed on the lower region of the second columnar silicon layer **231** and the region of the second planar silicon layer **233** positioned below the second columnar silicon layer **231**, and a second p+ type silicon layer **159** is formed on the upper region of the second columnar silicon layer **231**. In this embodiment, the first p+ type silicon layer **119**, for example, functions as a source scattering layer and the second p+ type silicon layer **159** functions as a drain scattering layer. In addition, the area between the source

scattering layer and the drawing scattering layer functions as a channel region. The second columnar silicon layer **231** between the first p+ type silicon layer **119** and the second p+ type silicon layer **159** functioning as this channel region is called a second silicon layer **120**.

[0064] A second gate insulating film **139** is formed surrounding the second columnar silicon layer **231** functioning as the channel region. The second gate insulating film **139** may be, for example, an oxide film, a nitride film or a high-k film. Furthermore, a second metal film **137** is formed surrounding this second gate insulating film **139**. The second metal film **137** may be, for example, titanium, titanium nitride, tantalum or tantalum nitride. Second polysilicon films **135** and **151** are formed surrounding this second metal film **137**. The second metal film **137** and the second polysilicon films **135** and **151** constitute a second gate electrode **235**. Thus, by using metal as the gate electrode, it is possible to control depletion of the channel region while also lowering the resistance of the gate electrode.

In the present embodiment, a channel is formed in the second silicon layer **120** by impressing a voltage on the second gate electrode **235** during operation.

[0065] In addition, a fourth metal-silicon compound **168**, a fifth metal-silicon compound **170** and a sixth metal-silicon compound **169** are respectively formed on the first p+ type silicon layer **119**, the second gate electrode **235** and the second p+ type silicon layer **159**. As the metal comprising the metal-silicon compounds, Ni or Co may be used, for example. Through these metal-silicon compounds, the first p+ type silicon layer **119**, the second gate electrode **235** and the second p+ type silicon layer **159** are connected to below-described contacts. Through this, the resistances of the gate, source and drain are lowered.

[0066] Furthermore, a fourth insulating film **129** is formed between the second gate electrode **235** and the second planar silicon layer **233**, a fifth insulating film **161** is formed in a sidewall shape on the upper sidewall of the second columnar silicon layer **231** and above the second gate electrode **235**, and a sixth insulating film **164** is formed in a sidewall shape on the sidewall of the second gate electrode **235** and the fourth insulating film **129**. The fourth insulating film **129** is preferably a low-k insulating film such as SiOF, SiOH or the like, for

example.

The parasitic capacitance between the gate electrode and the planar silicon layer is reduced by the fourth insulating film **129**.

[0067] The first n+ type silicon layer **113** is connected to a contact **230** via the first metal-silicon compound **172**. The contact **230** is formed from a barrier metal layer **189** and metal layers **194** and **199**. The contact **230** is further connected to a power source wire **225**. The power source wire **225** is composed of a barrier metal layer **216**, a metal layer **217** and a barrier metal layer **218**.

[0068] The second n+ type silicon layer **157** is connected to a contact **229** via the second metal-silicon compound **171**. The contact **229** is composed of a barrier metal layer **188** and metal layers **193** and **198**. The contact **229** is further connected to an output wire **223**. The output wire **223** is composed of a barrier metal layer **213**, a metal layer **214** and a barrier metal layer **215**.

[0069] The first gate electrode **236** is connected to a contact **228** via the third metal-silicon compound **170** and the second gate electrode **235** is connected to the contact **228** via the fifth metal-silicon compound **170**. The contact **228** is composed of a barrier metal layer **187** and metal layers **192** and **197**. The contact **228** is further connected to an input wire **224**. The input wire **224** is composed of a barrier metal layer **213**, a metal layer **214** and a barrier metal layer **215**.

[0070] The first p+ type silicon layer **119** is connected to a contact **226** via the fourth metal-silicon compound **168**. The contact **226** is formed from a barrier metal layer **185** and metal layers **190** and **195**. The contact **226** is further connected to a power source wire **222**. The power source wire **222** is composed of a barrier metal layer **207**, a metal layer **208** and a barrier metal layer **209**.

[0071] The second p+ type silicon layer **159** is connected to a contact **227** via the sixth metal-silicon compound **169**. The contact **227** is composed of a barrier metal layer **186** and metal layers **191** and **196**. The contact **227** is further connected to an output wire **223**. The

output wire **223** is composed of a barrier metal layer **213**, a metal layer **214** and a barrier metal layer **215**.

[0072] Through the above, an inverter circuit is composed from the pMOS SGT **219** and the nMOS SGT **220**.

[0073] Through this composition, lower resistance and downsizing of the semiconductor device are realized in the inverter circuit according to the present embodiment, and in addition, the parasitic capacitance between interlayer wires is reduced. Through this, it is possible to avoid slowing of operating speeds accompanying SGT downsizing.

[0074] In this embodiment, the first gate insulating film **140** and the first metal film **138** are preferably materials that make the nMOS SGT **220** enhancement-type, and the second gate insulating film **139** and the second metal film **137** are preferably materials that make the pMOS SGT **219** enhancement-type. The penetrating current that flows during operation of this inverter composed of the nMOS SGT **220** and the pMOS SGT **219** can thus be reduced.

[0075] In addition, in the nMOS SGT according to this embodiment, the thickness of the second insulating film **162** is preferably thicker than the sum of the thickness of the first gate insulating film **140** and the thickness of the first metal film **138**. In this case, the first gate insulating film **140** and the first metal film **138** are covered by the first columnar silicon layer **232**, the first polysilicon films **136** and **152**, the first insulating film **129** and the second insulating film **162**.

When the above-described composition is employed, the first metal film **138** is protected in its entirety and thus is not etched by a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture when the metal-semiconductor compound is formed.

[0076] In addition, in the pMOS SGT according to this embodiment, the thickness of the second insulating film **161** is preferably thicker than the sum of the thickness of the second gate insulating film **139** and the thickness of the second metal film **137**. In this case, the second gate insulating film **139** and the second metal film **137** are covered by the second columnar silicon layer **231**, the second polysilicon films **135** and **151**, the fourth insulating film **129** and the fifth

insulating film **161**.

When the above-described composition is employed, the second metal film **137** is protected in its entirety and thus is not etched by a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture when the metal-semiconductor compound is formed.

[0077] In addition, in the nMOS SGT according to this embodiment, the length from the center of the first columnar silicon layer **232** to the end of the first planar silicon layer **234** is preferably larger than the sum of the length from the center to the sidewall of the first columnar silicon layer **232**, the thickness of the first gate insulating film **140**, the thickness of the first gate electrode **236** and the thickness of the third insulating film **164**.

When the above-described composition is employed, the first metal-silicon compound **172** can be formed on the n+ type silicon layer **113** without adding any special manufacturing processes.

[0078] In addition, in the pMOS SGT according to this embodiment, the length from the center of the second columnar silicon layer **231** to the end of the second planar silicon layer **233** is preferably larger than the sum of the length from the center to the sidewall of the second columnar silicon layer **231**, the thickness of the second gate insulating film **139**, the thickness of the first gate electrode **235** and the thickness of the sixth insulating film **164**.

When the above-described composition is employed, the fourth metal-silicon compound **168** can be formed on the p+ type silicon layer **119** without adding any special manufacturing processes.

[0079] Next, one example of the manufacturing method for forming an inverter provided with SGTs according to the embodiments of the present invention will be described with reference to FIGS. 2A through 88D. In these drawings, the same constituent elements are labeled with the same reference numbers.

FIGS. 2A through 88D show an example of producing an SGT according to the present invention. In each drawing, part A shows a planar view, part B shows a cross-sectional view along line X-X', part C shows a cross-sectional view along line Y1-Y1' and part D shows a

cross-sectional view along line Y2-Y2'.

[0080] First, as shown in FIGS. 2A to 2D, a nitride film **103** is formed on a substrate composed of a silicon oxide film **101** and a silicon layer **102**. Here, the substrate may also be composed of silicon. In addition, an oxide film may be formed on the silicon layer and another silicon layer may be formed on the oxide film. In the present embodiment, an i-type silicon layer is used as the silicon layer **102**. When a p-type silicon layer and an n-type silicon layer are used in place of the i-type silicon layer, dopants are introduced into the part that becomes the channel of the SGT. In addition, a thin n-type silicon layer or a thin p-type silicon layer may be used in place of the i-type silicon layer.

[0081] Next, resists **104** and **105** for forming a hard mask for a columnar silicon layer are formed on the nitride film **103**, as shown in FIGS. 3A to 3D.

[0082] Next, the nitride film **103** is etched and hard masks **106** and **107** are formed, as shown in FIGS. 4A to 4D.

[0083] Next, the silicon layer **102** is etched and columnar silicon layers **231** and **232** are formed, as shown in FIGS. 5A to 5D.

[0084] Next, the resists **104** and **105** are removed. Conditions on the substrate following removal are shown in FIGS. 6A to 6D.

[0085] The surface of the silicon layer **102** is oxidized and a sacrificial oxide film **108** is formed, as shown in FIGS. 7A to 7D. By making this sacrificial oxide film, the surface of the silicon, such as carbon thrown in during silicon etching, is removed.

[0086] The sacrificial oxide film **108** is removed through etching to form the shape shown in FIGS. 8A to 8D.

[0087] An oxide film **109** is formed on the surface of the silicon layer **102** and the hard masks **106** and **107**, as shown in FIGS. 9A to 9D.

[0088] The oxide film **109** is etched and left in sidewall shape on the sidewall of the columnar silicon layers **231** and **232** to form sidewalls **110** and **111**, as shown in FIGS. 10A to 10D. When forming an n+ type silicon layer by injecting dopants surrounding the bottom of the

columnar silicon layer **231**, these sidewalls **110** and **111** prevent dopants from entering the channel, making it possible to control fluctuations in the threshold voltage of the SGT.

[0089] A resist **112** for injecting dopants into the bottom of the columnar silicon layer **232** is formed surrounding the columnar silicon layer **231**, as shown in FIGS. 11A to 11D.

[0090] As indicated by the arrows in FIGS. 12B and 12C, arsenic, for example, is injected into the silicon layer **102** in the region where the nMOS SGT is to be formed, thereby forming an n+ type silicon layer **113** surrounding the bottom of the columnar silicon layer **232**. At this time, the part of the silicon layer **102** covered by the hard mask **107** and the sidewall **111** does not become the n+ type silicon layer, comprising instead a first silicon layer **114** region in the columnar silicon layer **232**.

[0091] The resist **112** is removed. Conditions on the substrate following removal are shown in FIGS. 13A to 13D.

[0092] The sidewalls **110** and **111** are removed through etching. Conditions on the substrate following etching are shown in FIGS. 14A to 14D.

[0093] Annealing is accomplished and the injected dopants, here arsenic, are activated. Through this, the injected dopants are scattered to the bottom of the columnar silicon layer **232**, as shown in FIGS. 15A to 15D. Through this, even the bottom of the columnar silicon layer **231** becomes an n+ type silicon layer and forms a portion of the n+ type silicon layer **113**.

[0094] An oxide film **115** is formed on the silicon layer **102**, the hard masks **106** and **107** and the n+ type silicon layer **113**, as shown in FIGS. 16A to 16D.

[0095] The oxide film **115** is etched, leaving behind a sidewall shape in the sidewall of the columnar silicon layers **231** and **232** to form sidewalls **116** and **117**, as shown in FIGS. 17A to 17D. When forming a p+ type silicon layer by injecting dopants surrounding the bottom of the columnar silicon layer **231**, these sidewalls prevent dopants from entering the channel, making it possible to control fluctuations in the threshold voltage of the SGT.

[0096] A resist **118** is formed surrounding the columnar silicon layer **231** in order to inject dopants into the bottom of the columnar silicon layer **232**, as shown in FIGS. 18A to 18D.

[0097] As indicated by the arrows in FIGS. 19B and 19D, boron, for example, is injected into the silicon layer **102** in the region where the pMOS SGT is to be formed, thereby forming a p+ type silicon layer **119** surrounding the bottom of the columnar silicon layer **231**. At this time, the part of the silicon layer **102** covered by the hard mask **106** and the sidewall **116** does not become the p+ type silicon layer, comprising instead a second silicon layer **120** region in the columnar silicon layer **231**.

[0098] The resist **118** is removed. Conditions on the substrate following removal are shown in FIGS. 20A to 20D.

[0099] The sidewalls **116** and **117** are removed through etching. Conditions on the substrate following etching are shown in FIGS. 21A to 21D.

[0100] Annealing is accomplished and the injected dopant, here boron, is activated. Through this, the injected dopant is scattered to the bottom of the columnar silicon layer **231**, as shown in FIGS. 22A to 22D. Through this, even the bottom of the columnar silicon layer **231** becomes a p+ type silicon layer and forms a portion of the p+ type silicon layer **119**.

[0101] An oxide film **121** is formed on the surface of the hard masks **106** and **107**, the n+ type silicon layer **113** and the p+ type silicon layer **119**, as shown in FIGS 23A to 23D. This oxide film **121** protects the first silicon layer **114** and the second silicon layer **120** from resist for forming a planar silicon layer later.

[0102] Resists **122** and **123** for forming a planar silicon layer are formed. The resists **122** and **123** are formed so as to cover the second silicon layer **120** and the area surrounding the bottom thereof, and the first silicon layer **114** and the area surrounding the bottom thereof, respectively, as shown in FIGS. 24A to 24D.

[0103] The oxide film **121** is etched and partitioned into oxide films **124** and **125**, as shown in FIGS. 25A to 25D.

[0104] Portions of the p+ type silicon layer **119** and of the n+ type silicon layer **113** are etched to form planar silicon layers **233** and **234**, as shown in FIGS. 26A and 26D. The planar silicon layer **233** is the planar portion of the p+ type silicon layer **119** arranged surrounding the

area immediately below the second silicon layer **120**. In addition, the planar silicon layer **234** is the planar portion of the n+ type silicon layer **113** arranged surrounding the area immediately below the first silicon layer **114**.

[0105] The resists **122** and **123** are removed. Conditions on the substrate following removal are shown in FIGS. 27A to 27D.

[0106] An oxide film **123** is formed on the surface of the resists **122** and **123** and the planar silicon layers **233** and **244**, as shown in FIGS. 28A to 28D.

[0107] CMP (Chemical Mechanical Polishing) is accomplished, the oxide film **126** is planarized and the hard masks **106** and **107** are exposed, as shown in FIGS. 29A to 29D.

[0108] The oxide films **126**, **124** and **125** are etched to form an oxide film **126** buried between the planar silicon layers **119** and **133**, as shown in FIGS. 30A to 30D.

[0109] An oxide film **128** is formed on the result of the above processes. At this time, the oxide film **128** is formed thickly on the n+ type silicon layer **113**, the p+ type silicon layer **119**, the oxide film **126** and the hard masks **106** and **107**, and the oxide film **128** is formed thinly on the sidewalls of the columnar silicon layers **231**and **232**, as shown in FIGS. 31A to 31D.

[0110] The oxide film **128** formed on the sidewalls of the columnar silicon layers **231** and **232** is removed through etching. The etching is preferably isotropic etching. The oxide film **128** is formed thickly on the n+ type silicon layer **113**, the p+ type silicon layer **119**, the oxide film **126** and the hard masks **106** and **107** and the oxide film **128** is formed thinly on the sidewalls of the columnar silicon layers **213** and **232**, and consequently, the oxide film **128** remains on the n+ type silicon layer **113**, the p+ type silicon layer **119** and the oxide film **126**, forming an insulating film **129**, as shown in FIGS. 32A to 32D. In addition, in this case oxide films **130** and **131** remain on the hard masks **106** and **107** as well.

By means of the insulating film **129**, it is possible to reduce the parasitic capacitance between the gate electrode and the planar silicon layer.

[0111] A gate insulating film **132** is formed so as to cover at least the first silicon layer **114** and the surface of the surroundings of the bottom thereof and the second silicon layer **120** and

the surface of the surroundings of the bottom thereof, as shown in FIGS. 33A to 33D. The gate insulating film **132** is a film containing at least one out of an oxide film, a nitride film and a high-k film. In addition, prior to forming the gate insulating film, hydrogen atmosphere annealing or epitaxial growth may be accomplished on the columnar silicon layers **231** and **232**.

[0112] A metal film **133** is formed on the surface of the gate insulating film **132**, as shown in FIGS. 34A to 34D. The metal film is preferably a film containing titanium, titanium nitride, tantalum or tantalum nitride. By using the metal film, it is possible to control depletion of the channel region and it is also possible to lower the resistance of the gate electrode. It is necessary to use a manufacturing process for later processes so as to control metal contamination by the metal gate electrode.

[0113] A polysilicon film **134** is formed on the surface of the metal film **133**, as shown in FIGS. 35A to 35D. In order to control metal contamination, it is preferable to form the polysilicon film **134** using normal-pressure CVD.

[0114] The polysilicon film **134** is etched to form polysilicon films **135** and **136** remaining in sidewall shape, as shown in FIGS. 36A to 36D.

[0115] The metal film **133** is etched. The metal film on the sidewalls of the columnar silicon layers **231** and **232** is protected by the polysilicon films **135** and **136** and thus is not etched, and becomes the metal films **137** and **138** remaining in sidewall shape, as shown in FIGS. 37A to 37D.

[0116] The gate insulating film **132** is etched. The gate insulating film on the sidewalls of the columnar silicon layers **231** and **232** is protected by the polysilicon films **135** and **136** and thus is not etched, and becomes the gate insulating film **140** remaining in sidewall shape, as shown in FIGS. 38A to 38D.

[0117] A polysilicon film **141** is formed on the surface where circuits are formed, as shown in FIGS. 39A to 39D. In order to control metal contamination, the polysilicon film **141** is preferably formed using normal-pressure CVD.

When a high-k film is used in the gate insulating films **134** and **140**, this high-k film

can be the source of metal contamination.

Through this polysilicon film **141**, the gate insulating film **139** and the metal film **137** are covered by the columnar silicon layer **231**, the polysilicon films **135** and **141**, the insulating film **129** and the hard mask **106**.

In addition, the gate insulating film **140** and the metal film **138** are covered by the columnar silicon layer **232**, the polysilicon films **136** and **141**, the insulating film **129** and the hard mask **107**.

That is to say, the gate insulating films **139** and **140** and the metal films **137** and **138**, which are all sources of contamination, are covered by the columnar silicon layers **231** and **232**, the polysilicon layers **135**, **136** and **141**, the insulating film **129** and the hard masks **106** and **107**, so it is possible to control metal contamination by metal contained in the gate insulating films **139** and **140** and the metal films **137** and **138**.

In order to achieve the aforementioned objectives, it would be fine to form a structure in which the metal film is thickly formed, etching is accomplished to leave a sidewall shape and the gate insulating film is etched, following which a polysilicon film is formed and the gate insulating film and the metal film are covered by the columnar silicon layer, the polysilicon layer, the insulating film and the hard mask.

[0118] A polysilicon film **142** is formed on the surface where the circuits are formed, as shown in FIGS. 40A to 40D. In order to bury the columnar silicon **231** and **232**, the polysilicon film is preferably formed using low-pressure CVD. The gate insulating film and the metal film that are the source of contamination are covered by the columnar silicon layers **231** and **232**, the polysilicon layers **135**, **136** and **141**, the insulating film **129** and the hard masks **106** and **107**, so it is possible to use low-pressure CVD.

[0119] CMP (chemical mechanical polishing) is accomplished with the oxide films **130** and **131** and polishing steppers, as shown in FIGS. 41A to 41D, and the polysilicon film **142** is planarized, as shown in FIGS. 41A to 41D. Because the polysilicon film is planarized, it is possible to control metal contamination of the CMP device.

[0120] The oxide films **130** and **131** are removed through etching. Conditions on the substrate following etching are shown in FIGS. 42A to 42D

[0121] The polysilicon film **142** is etched and the polysilicon film **142** is removed to the top edge of the region where the gate electrode and the gate insulating films **139** and **140** are to be formed, as shown in FIGS. 43A to 43D. Through this etching, the gate length of the SGT is determined.

[0122] The metal films **137** and **138** on the upper sidewalls of the columnar silicon layers **231** and **232** are removed through etching. Conditions on the substrate following etching are shown in FIGS. 44A to 44D.

[0123] The gate insulating films **139** and **140** on the upper sidewalls of the columnar silicon layers **231** and **232** are removed through etching. Conditions on the substrate following etching are shown in FIGS. 45A to 45D

[0124] An oxide film **144** is formed on the surface where the circuits are formed, as shown in FIGS. 46A to 46D. Because the gate electrode top surface is protected by this oxide film **144** from the wet treatment or dry treatment accomplished in later processes, it is possible to control fluctuations in gate length, that is to say variance in gate length, and damage to the gate insulating films **139** and **140** and the metal films **137** and **138** from the gate electrode top surface.

[0125] A nitride film **145** is formed on the surface of the oxide film **144**, as shown in FIGS. 47A to 47D.

[0126] The nitride film **145** and the oxide film **144** are etched to form the oxide films **148** and **149** and the nitride films **146** and **147** remaining in a sidewall shape, as shown in FIGS. 48A to 48D.

The sum of the film thicknesses of the oxide film **148** and the nitride film **146** remaining in sidewall shape is the film thickness of the gate electrode **235** later, and the film thickness of the oxide film **149** and the nitride film **147** remaining in sidewall shape is the film thickness of the gate electrode **236** later, so by adjusting the film formation thicknesses and etching conditions of the oxide film **144** and the nitride film **145**, it is possible to form a gate

electrode of the desired film thickness.

In addition, it is preferable for the sum of the radius of the columnar silicon layer **231** and the sum of the film thicknesses of the oxide film **148** and the nitride film **146** remaining in sidewall shape to be greater than the radius of the outer circumference of the cylinder composed by the gate insulating film **139** and the metal film **137**, and for the sum of the radius of the columnar silicon layer **232** and the sum of the film thicknesses of the oxide film **149** and the nitride film **147** remaining in sidewall shape to be larger than the diameter of the outer circumference of the cylinder composed by the gate insulating film **140** and the metal film **138**. At this time, because the metal films **137** and **138** are covered by the polysilicon film after gate etching, it is possible to control metal contamination.

[0127] A resist **150** for forming a gate wire **221** is formed on the polysilicon layer **142** at least between the first silicon layer **114** and the second silicon layer **120**, as shown in FIGS. 49A to 49D.

[0128] The polysilicon films **142**, **141**, **135** and **136** are etched to form gate electrodes **235** and **236** and the gate wire **221**, as shown in FIGS. 50A to 50D.

The gate electrode **235** is composed of the metal film **137** and the polysilicon films **135** and **151**, and the gate electrode **236** is composed of the metal film **138** and the polysilicon films **136** and **152**.

The gate wire **221** connecting the gate electrodes **235** and **236** is composed of the polysilicon films **135**, **151**, **142**, **152** and **136**.

[0129] The insulating film **129** is etched and the surfaces of the p+ type silicon layer **119** and the n+ type silicon layer **113** are exposed, as shown in FIGS. 51A to 51D.

[0130] The resist **150** is removed. Conditions on the substrate following removal are shown in FIGS. 52A to 52D.

[0131] Oxidation is accomplished to form oxide films **153**, **154** and **155**, as shown in FIGS. 53A to 53D. The p+ type silicon layer **159**, the n+ type silicon layer **157**, the gate electrodes **235** and **236** and the gate wire **221** are protected by these nitride films from etching through wet

treatment or dry treatment during etching of the hard masks **106** and **107** and the nitride films **146** and **147** performed later.

[0132] The hard masks **106** and **107** and the nitride films **146** and **147** are removed by etching through a wet treatment or dry treatment. Conditions on the substrate following etching are shown in FIGS. 54A to 54D. Because the top surface of the gate electrodes is protected from the wet treatment or dry treatment by the oxide films **148** and **149**, it is possible to control fluctuations in gate length, that is to say variances in gate length, and to control damage to the gate insulating films **139** and **140** and the metal films **137** and **138** from the top surface of the gate electrode. At this time, the gate insulating films **139** and **140** and metal films **137** and **138** are covered by the polysilicon **135**, **136**, **151** and **152**, the nitride films **148** and **149**, the columnar silicon layers **231** and **232** and the insulating film **129**, so metal contamination of the nitride film wet etching device is controlled.

[0133] The oxide films **148**, **149**, **153**, **154** and **155** are removed by etching. Conditions on the substrate following etching are shown in FIGS. 55A to 55D.

[0134] A resist **156** for forming an n+ type silicon layer on the columnar silicon layer **232** through dopant injection is formed surrounding the columnar silicon layer **231**, as shown in FIGS. 56A to 56D. In advance of this process, a thin oxide film may be formed as a through (?) oxide film for dopant injection.

[0135] As indicated by the arrows in FIGS. 57B and 57C, arsenic, for example, is injected into the top of the columnar silicon layer **232** to form an n+ type silicon layer **157**. The angle of injecting the arsenic is preferably 10 degrees to 60 degrees, and more preferably the large angle of 60 degrees, where a line orthogonal to the substrate is taken as 0 degrees. By injecting the arsenic at a large angle, the n+ type silicon layers **157** and the gate electrode **236** are given an overlap and it is possible to minimize this overlap.

[0136] The resist **156** is removed. Conditions on the substrate following removal are shown in FIGS. 58A to 58D.

[0137] Heat treatment is accomplished and the arsenic is activated. Conditions on the

substrate following activation is shown in FIGS. 59A to 59D.

[0138] A resist **158** for forming a p+ type silicon layer on the upper part of the columnar silicon layer **231** through dopant injection is formed surrounding the columnar silicon layer **232**, as shown by FIGS. 60A to 60D.

[0139] As indicated by FIGS. 61B and 61D, boron, for example, is injected into the upper part of the columnar silicon layer **231** to form a p+ type silicon layer **159**. The angle of injecting the boron is preferably 10 degrees to 60 degrees, and more preferably the large angle of 60 degrees, where a line orthogonal to the substrate is taken as 0 degrees. By injecting the boron at a large angle, the p+ type silicon layers **159** and the gate electrode **235** are given an overlap and it is possible to minimize this overlap.

[0140] The resist **158** is removed. Conditions on the substrate following removal are shown in FIGS. 62A to 62D.

[0141] Heat treatment is accomplished and the boron is activated. Conditions on the substrate following activation is shown in FIGS. 63A to 63D. By separately undertaking heat treatment of the n+ type silicon layer **157** and heat treatment of the p+ type silicon layer **159**, it is possible to easily optimize heat treatment conditions for each, so it is possible to control the short channel effect and to control leak current.

[0142] A nitride film **160** is formed on the surface where the circuits are formed, as shown in FIGS. 64A to 64D.

[0143] The nitride film **160** is etched to form an insulating film **161** composed of nitride film formed in a sidewall shape on the upper sidewall of the columnar silicon layer **231** and the upper part of the gate electrode **235**, an insulating film **162** composed of a nitride film formed in a sidewall shape on the upper sidewall of the columnar silicon layer **232** and the upper part of the gate electrode **236**, an insulating film **164** composed of a nitride film formed in a sidewall shape on the sidewalls of the insulating film **129** and the gate electrodes **235** and **236**, an insulating film **163** composed of a nitride film formed in a sidewall shape on the sidewall of the p+ type silicon layer **119** and an insulating film **165** composed of a nitride film formed in a sidewall shape on

the sidewall of the n+ type silicon layer **113**, as shown in FIGS. 65A to 65D.

By making the thicknesses of the insulating films **161** and **162** formed in a sidewall shape on the upper sidewalls of the columnar semiconductor layers and the upper parts of the gate electrodes thicker than the sum of the thicknesses of the gate insulating films **139** and **140** and the thicknesses of the metal films **137** and **138**, the gate insulating film **140** and the metal film **138** are covered by the columnar silicon layer **232**, the polysilicon layers **136** and **152**, the insulating film **129** and the insulating film **162**, and in addition, the gate insulating film **129** and the metal film **137** are covered by the columnar silicon layer **231**, the polysilicon layers **135** and **151**, the insulating film **129** and the insulating film **161**.

[0144] A resist **166** for forming a deep n+ type silicon layer in the direction orthogonal to the substrate on the upper part of the columnar silicon layer **232** through dopant injection is formed surrounding the columnar silicon layer **231**, as shown in FIGS. 66A to 66D. By making this an n+ type silicon layer deep in the direction orthogonal to the substrate, it is possible to form a metal-silicon compound later on the n+ type silicon layer. If this were an n+ type silicon layer shallow in the direction orthogonal to the substrate, the metal-silicon compound formed later would be formed on the n+ type silicon layer and the first silicon layer and would become a source of leak current.

[0145] As shown in FIGS. 67B and 67C, arsenic, for example, is injected into the upper part of the columnar silicon layer **232** and the n+ type silicon layer **157** is made deep in the direction orthogonal to the substrate. The angle of injecting the arsenic is preferably a low angle of 0 degrees to 7 degrees, where the line orthogonal to the substrate is taken to be 0 degrees. By injecting the arsenic at a low angle, it is possible to form an n+ type silicon layer deep in the direction orthogonal to the substrate on the upper part of the columnar silicon layer of the nMOS SGT.

[0146] The resist **166** is removed. Conditions on the substrate following removal are shown in FIGS. 68A to 68D.

[0147] A resist **167** for forming a deep p+ type silicon layer in the direction orthogonal to

the substrate on the upper part of the columnar silicon layer **231** through dopant injection is formed surrounding the columnar silicon layer **232**, as shown in FIGS. 69A to 69D. By making this a p+ type silicon layer deep in the direction orthogonal to the substrate, it is possible to form a metal-silicon compound later on the p+ type silicon layer. If this were a p+ type silicon layer shallow in the direction orthogonal to the substrate, the metal-silicon compound formed later would be formed on the p+ type silicon layer and the second silicon layer and would become a source of leak current.

[0148] As shown in FIGS. 70B and 70D, boron, for example, is injected into the upper part of the columnar silicon layer **231** and the p+ type silicon layer **159** is made deep in the direction orthogonal to the substrate. The angle of injecting the boron is preferably a low angle of 0 degrees to 7 degrees, where the line orthogonal to the substrate is taken to be 0 degrees. By injecting the boron at a low angle, it is possible to form a p+ type silicon layer deep in the direction orthogonal to the substrate on the upper part of the columnar silicon layer of the pMOS SGT.

[0149] The resist **167** is removed. Conditions on the substrate following removal are shown in FIGS. 71A to 71D.

[0150] Heat treatment is accomplished in order to activate the dopant. Conditions following activation are shown in FIGS. 72A to 72D.

[0151] By sputtering a metal such as Ni or Co and adding heat treatment, a metal-silicon compound is formed on the surface of the p+ type silicon layer **119**, the p+ type silicon layer **159**, the gate electrode **235**, the n+ type silicon layer **113**, the n+ type silicon layer **157** and the gate electrode **236**, and by removing the unreacted metal film using a sulfuric acid hydrogen peroxide mixture or an ammonia hydrogen peroxide mixture, a metal-silicon compound **168** is formed on the surface of the p+ type silicon layer **119**, a metal-silicon compound **169** is formed on the surface of the p+ type silicon layer **159**, a metal-silicon compound **170** is formed on the surface of the gate electrode **235**, the gate wire **221** and the gate electrode **236**, a metal-silicon compound **172** is formed on the surface of the n+ type silicon layer **113**, and a metal-silicon compound **171**

is formed on the surface of the n+ type silicon layer **157**.

The gate insulating film **140** and the metal film **138** are covered by the columnar silicon layer **232**, the polysilicon films **136** and **152**, the insulating film **129** and the insulating film **162**, and in addition, the gate insulating film **139** and the metal film **137** are covered by the columnar silicon layer **231**, the polysilicon films **135** and **151**, the insulating film **129** and the insulating film **161**, so the metal films **137** and **138** are not etched by the sulfuric acid hydrogen peroxide mixture or ammonia hydrogen peroxide mixture.

In other words, by using the structure of the present invention, it is possible to use metal in the gate electrode, it is possible to control depletion of the channel region, it is possible to lower the resistance of the gate electrode and it is possible to lower the resistance of the gate, source and drain through a metal-silicon compound.

Normally, the natural oxide film on the surface of the silicon layer is removed by hydrofluoric acid as a pre-treatment prior to sputtering the metal such as Ni or Co. At this time, the insulating film **129** composed of an oxide film is protected from the hydrofluoric acid by the insulating film **164** composed of a nitride film formed in a sidewall shape on the sidewall.

[0152] A contact stopper **173** of nitride film is formed, an interlayer insulating film **174** is deposited and planarization is undertaken, as shown in FIGS. 74A to 74D.

[0153] A resist **175** for forming contact holes is formed above the columnar silicon layers **231** and **232**, as shown in FIGS. 75A to 75D.

[0154] The interlayer insulating film **174** is etched to form contact holes **176** and **177** above the columnar silicon layer **232**, as shown in FIGS. 76A to 76D.

[0155] The resist **175** is removed. Conditions on the substrate following removal are shown in FIGS. 77A to 77D.

[0156] A resist **178** for forming contact holes above the planar silicon layers **233** and **234** and above the gate wire **221** is formed, as shown in FIGS. 78A to 78D.

[0157] The interlayer insulating film **174** is etched to form contact holes **179**, **180** and **181** above the planar silicon layers **233** and **234** and above the gate wire **221**, respectively, as shown

in FIGS. 79A to 79D.

Because the contact holes **176** and **177** above the columnar silicon **231** and **232** and the contact holes **179**, **180** and **181** above the planar silicon layers **233** and **234** and above the gate wire **221** are formed through different processes, the etching conditions for forming the contact holes **176** and **177** above the columnar silicon **231** and **232** and the etching conditions for forming the contact holes **179**, **180** and **181** above the planar silicon layers **233** and **234** and above the gate wire **221** can each be optimized.

[0158] The resist **178** is removed. Conditions on the substrate following removal are shown in FIGS. 80A to 80D.

[0159] A contact stopper **173** is etched below the contact holes **179**, **176**, **180**, **177** and **181**. Conditions on the substrate following etching are shown in FIGS. 81A to 81D.

[0160] After a barrier metal layer **182** is deposited on the surface where the circuits are formed, a metal **183** is deposited on the top thereof, as shown in FIGS. 82A to 82D.

[0161] A metal **184** is deposited to bury the gap, as shown in FIGS. 83A to 83D.

[0162] The metals **184** and **183** and the barrier metal layer **182** are planarized and etched to form contacts **226**, **227**, **228**, **229** and **230**, as shown in FIGS. 84A to 84D. The contact **226** is composed of a barrier metal layer **185** and metal layers **190** and **195**. The contact **227** is composed of a barrier metal layer **186** and metal layers **191** and **196**. The contact **228** is composed of a barrier metal layer **187** and metal layers **192** and **197**. The contact **229** is composed of a barrier metal layer **188** and metal layers **193** and **198**. The contact **230** is composed of a barrier metal layer **189** and metal layers **194** and **199**.

[0163] A barrier metal layer **200**, a metal layer **201** and a barrier metal layer **202** are deposited in this order on the planarized surface, as shown in FIGS. 85A to 85D.

[0164] Resists **203**, **204**, **205** and **206** for forming a power source wire, an input wire and an output wire are formed, as shown in FIGS. 86A to 86D.

[0165] The barrier metal layer **202**, the metal **201** and the barrier metal layer **200** are etched to form power source wires **222** and **225**, an input wire **224** and an output wire **223**, as shown in

FIGS 87A to 87D. The power source wire **222** is composed of a barrier metal layer **207**, a metal layer **208** and a barrier metal layer **209**. The power source wire **225** is composed of a barrier metal layer **216**, a metal layer **217** and a barrier metal layer **218**. The input wire **224** is composed of a barrier metal layer **213**, a metal layer **214** and a barrier metal layer **215**. The output wire **223** is composed of a barrier metal layer **210**, a metal layer **211** and a barrier metal layer **212**.

[0166] The resists **203**, **204**, **205** and **206** are removed. Conditions on the substrate following removal are shown in FIGS. 88A to 88D.

[0167] With the above production method, it is possible to produce a semiconductor device with a small parasitic capacitance between the gate electrode and the planar silicon layers because of the first and fourth insulating films.

[0168] Having described and illustrated the principles of this application by reference to one (or more) preferred embodiment(s), it should be apparent that the preferred embodiment(s) may be modified in arrangement and detail without departing from the principles disclosed herein and that it is intended that the application be construed as including all such modifications and variations insofar as they come within the spirit and scope of the subject matter disclosed herein.

CLAIMS

What is claimed is:

1. A semiconductor device provided with:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the first planar semiconductor layer and the lower region of the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround the upper region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film;

a first contact formed above the first columnar semiconductor layer;

a second contact formed above the first planar semiconductor layer; and

a third contact formed above the first gate electrode;

wherein the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film.

2. The semiconductor device according to Claim 1, wherein the thickness of the second insulating film is thicker than the sum of the thickness of the first gate insulating film and the thickness of the first metal film.

3. The semiconductor device according to Claim 1 or Claim 2, further comprising a first metal-semiconductor compound formed on the upper surface of the first high concentration semiconductor layer.

4. The semiconductor device according to any of Claims 1 through 3, wherein the length from the center of the first columnar semiconductor layer to the edge of the first planar semiconductor layer is larger than the sum of the length from the center to the sidewall of the first columnar semiconductor layer, the thickness of the first gate insulating film, the thickness of the first gate electrode and the thickness of the third insulating film.

5. The semiconductor device according to any of Claims 1 through 4, further comprising a third metal-semiconductor compound formed on the top surface of the first gate electrode.

6. The semiconductor device according to any of Claims 1 through 5, further comprising a second metal-semiconductor compound formed on the top surface of the second high concentration semiconductor layer.

7. A semiconductor device comprising a first transistor and a second transistor, wherein:

the first transistor comprises:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer of second conductive type formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of second conductive type formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround both regions of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film;

a first metal-semiconductor compound formed on the top surface of the portion of the first high concentration semiconductor layer formed in the region below the first columnar semiconductor layer;

a third metal-semiconductor compound formed on the top surface of the first gate electrode; and,

a second metal-semiconductor compound formed on the top surface of the second high concentration semiconductor layer;

and the second transistor comprises:

a second planar semiconductor layer;

a second columnar semiconductor layer formed on the second planar semiconductor layer;

a third high concentration semiconductor layer of first conductive type formed on the lower region of the second columnar semiconductor layer and on the region of the second planar semiconductor layer below the second columnar semiconductor layer;

a fourth high concentration semiconductor layer of first conductive type formed on the upper region of the second columnar semiconductor layer;

a second gate insulating film formed on the sidewall of the second columnar semiconductor layer between the third high concentration semiconductor layer and the fourth high concentration semiconductor layer, so as to surround the second columnar semiconductor layer;

a second metal film formed on the second gate insulating film so as to surround the second gate insulating film;

a second semiconductor film formed on the second metal film so as to surround the second metal film;

a second gate electrode composed of the second metal film and the second semiconductor film;

a fourth insulating film formed between the second gate electrode and the second planar semiconductor layer;

a fifth insulating film formed in sidewall shape contacting the upper sidewall of the second columnar semiconductor layer and the top surface of the second gate electrode so as to surround the top region of the second columnar semiconductor layer;

a sixth insulating film formed in a sidewall shape contacting the sidewall of the fourth insulating film and the second gate electrode so as to surround the second gate electrode and the fourth insulating film;

a fourth metal-semiconductor compound formed on the top surface of the portion of the third high concentration semiconductor layer formed in the region below the second columnar semiconductor layer;

a fifth metal-semiconductor compound formed on the top surface of the second gate electrode; and,

a sixth metal-semiconductor compound formed on the top surface of the fourth high concentration semiconductor layer;

wherein the first gate insulating film and the first metal film are covered by the first columnar semiconductor layer, the first semiconductor film, the first insulating film and the second insulating film, and

the second gate insulating film and the second metal film are covered by the second columnar semiconductor layer, the second semiconductor film, the fourth insulating film and the fifth insulating film.

8. The semiconductor device according to Claim 7, wherein the first gate insulating film and the first metal film are formed from materials that make the first transistor enhancement-type, and

the second gate insulating film and the second metal film are formed from materials that make the second transistor enhancement-type.

9. The semiconductor device according to Claim 7 or Claim 8, wherein the thickness of the second insulating film is thicker than the sum of the thickness of the first gate insulating film and the thickness of the first metal film.

10. The semiconductor device according to any of Claims 7 through 9, wherein the length from the center of the first columnar semiconductor layer to the edge of the first planar semiconductor layer is larger than the sum of the length from the center to the sidewall of the

first columnar semiconductor layer, the thickness of the first gate insulating film, the thickness of the first gate electrode and the thickness of the third insulating film.

11. The semiconductor device according to any of Claims 7 through 10, wherein:

the first conductive type is n+ type,

the second conductive type is p+ type, and

the first and second columnar semiconductor layers and the first and second planar semiconductor layers are made of silicon.

12. A semiconductor device production method, being a method of producing the semiconductor device according to Claim 1 and comprising:

a process for preparing a first structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer and a hard mask formed on the top surface of the first columnar semiconductor;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer; and

a first insulating film formed on the first planar semiconductor layer;

a process for forming a seventh insulating film, a third metal film and a third semiconductor film, in that order, on the first structure;

a process for etching the third semiconductor film and leaving a sidewall shape on the sidewall on the first columnar semiconductor layer;

a process for etching the third metal film and leaving a sidewall shape on the sidewall of the first columnar semiconductor layer;

a seventh insulating film etching process for etching the seventh insulating film and leaving a sidewall shape on the sidewall of the first columnar semiconductor layer; and

a fourth semiconductor film formation process for forming a fourth semiconductor film on the result of the seventh insulating film etching process.

13. The semiconductor device production method according to Claim 12, further comprising:

a process for planarizing the fourth semiconductor film and the third semiconductor film in the result of the fourth semiconductor film formation process and exposing the upper region of the first metal film;

a first metal film and first gate insulating film formation process for etching the third metal film and the seventh insulating film so that the upper sidewall of the first columnar semiconductor layer is exposed to form the first metal film and the first gate insulating film; and,

a process for forming a first oxide film on the result of the first metal film and first gate insulating film formation process.

14. A semiconductor device production method, being a method of producing the semiconductor device according to Claim 1 and comprising:

a process for preparing a second structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall in the middle region of the first columnar semiconductor layer so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film; and

a first insulating film formed between the first gate electrode and the first planar semiconductor layer; and

a process for forming a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer on the upper region of the first columnar semiconductor layer on the second structure by injecting a dopant at an angle of 10 degrees to 60 degrees, with a line orthogonal to the substrate being 0 degrees.

15. A semiconductor device production method, being a method of producing the semiconductor device according to Claim 1 and comprising:

a process for preparing a third structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film; and

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a process for forming an eighth insulating film on the third structure; and

a process for forming a second insulating film by etching the eighth insulating film in a sidewall shape so the eighth insulating film remains on the top surface of the first gate electrode and the upper sidewall of the first columnar semiconductor layer.

16. A semiconductor device production method, being a method of producing the semiconductor device according to Claim 1 and comprising:

a process for preparing a fourth structure having:

a first planar semiconductor layer;

a first columnar semiconductor layer formed on the first planar semiconductor layer;

a first high concentration semiconductor layer formed on the lower region of the first columnar semiconductor layer and on the region of the first planar semiconductor layer below the first columnar semiconductor layer;

a second high concentration semiconductor layer of the same conductive type as the first high concentration semiconductor layer, formed on the upper region of the first columnar semiconductor layer;

a first gate insulating film formed on the sidewall of the first columnar semiconductor layer between the first high concentration semiconductor layer and the second high concentration semiconductor layer, so as to surround the first columnar semiconductor layer;

a first metal film formed on the first gate insulating film so as to surround the first gate insulating film;

a first semiconductor film formed on the first metal film so as to surround the first metal film;

a first gate electrode composed of the first metal film and the first semiconductor film;

a first insulating film formed between the first gate electrode and the first planar semiconductor layer;

a second insulating film formed in sidewall shape contacting the upper sidewall of the first columnar semiconductor layer and the top surface of the first gate electrode so as to surround the top region of the first columnar semiconductor layer;

a third insulating film formed in a sidewall shape contacting the sidewall of the first insulating film and the first gate electrode so as to surround the first gate electrode and the first insulating film; and

a first gate wire connected to the first gate electrode;

a contact stopper formation process for forming a contact stopper on the fourth structure;

a process for forming an interlayer insulating film so as to bury the result of the contact stopper formation process;

a process for forming a first resist on the interlayer insulating film, excluding on top of the first columnar semiconductor layer;

a process for etching the interlayer insulating film and forming a first contact hole on the interlayer insulating film;

a first resist removal process for removing the first resist;

a process for forming a second resist on the result of the first resist removal process, excluding on the first planar semiconductor layer and on the first gate wire;

a process for etching the interlayer insulating film and forming a second contact hole on top of the first planar semiconductor layer and forming a third contact hole on top of the first gate wire, on the interlayer insulating film;

a process for removing the second resist; and

a process for forming a first contact positioned above the first columnar semiconductor layer, a second contact positioned above the first planar semiconductor layer and a third contact positioned above the first gate wire on the first contact hole, the second contact hole and the third contact hole, respectively.